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Journal Name:	Journal of Materials Science Research and Reviews
Manuscript Number:	Ms_JMSRR_47106
Title of the Manuscript:	Effect of Annealing and Thickness on Some Physical Characteristics of ZnO Films
Type of the Article	Original Research Article

General guideline for Peer Review process:

This journal's peer review policy states that <u>NO</u> manuscript should be rejected only on the basis of '<u>lack of Novelty'</u>, provided the manuscript is scientifically robust and technically sound. To know the complete guideline for Peer Review process, reviewers are requested to visit this link:

(http://www.sciencedomain.org/page.php?id=sdi-general-editorial-policy#Peer-Review-Guideline)

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PART 1: Review Comments

	Reviewer's comment :	Author's comment (if agreed with reviewer, correct the manuscript and highlight that part in the manuscript. It is mandatory that authors should write his/her feedback here)
<u>Compulsory</u> REVISION comments	The state of the s	
	The authors are trying to synthesize different ZnO films with different thicknesses and study	
	its optical and structural properties. However, the current work is substandard and should	
	not be accepted in its current form.	
	1. The English of this manuscript is seriously bad. Therefore it is strongly advised to	
	rewrite most of the parts of the manuscript.	
	2. Abstract should be carefully rewritten according to the finding of the work.	
	3. In experimental part the authors have written the substrate was preheated at	
	400oC prior to the coating. Please explain why it was done?	
	4. The authors have written in the experiment that they got highly adhesive ZnO film.	
	How did the authors confirm about the adhesiveness of the films. Provide the	
	sufficient proofs in the manuscript. For example: SEM microstructure of film cross-	
	sections, or any adhesive tape test result as per ASTM standard.	
	5. The authors have reported that they measured the film thickness by gravimetric	
	method. I have doubt about the measurement by this method. It is strongly	
	suggested to clarify the thickness measurement with sufficient proof.	
	6. In structural characterization section the authors have mention that "strongest	
	peaksstructure of ZnO". How can authors attribute all the ZnO peaks as the	
	strongest?	
	7. How the authors confirm that "better crystallinity is proportional to the thickness"? Please clarify.	
	8. In throughout the manuscript the authors have said that all films are annealed at	
	500 °C. But, they have not mention about the annealing time and also the	
	procedure. Please clarify about the annealing atmosphere also.	
	9. Why the strain (%) is same in both as-deposited and annealed 410nm ZnO film?	
	10. How the grain sizes of the films were calculated? The authors are saying that they	
	have calculated crystallite size from Scherrer formula. The reviewer wants to	
	convey that the crystallite size and the grain size are completely different entity.	

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	Please explain.	
	11. Thickness is proportional to photon energywhy?	
	12. Which samples are showing better optical properties as-deposited or annealed? Please explain if no, then why annealing is required?	
	13. The conclusion should be clearly re-written with important observations and findings of the work	
Minor REVISION comments		
Optional/General comments		

PART 2:

		Author's comment (if agreed with reviewer, correct the manuscript and highlight that part in the manuscript. It is mandatory that authors should write his/her feedback here)
Are there ethical issues in this manuscript?	(If yes, Kindly please write down the ethical issues here in details)	

Reviewer Details:

Name:	Harekrushna Sutar
Department, University & Country	Indira Gandhi Institute of Technology, India

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